LASER TEXTURING APPARATUS WITH DUAL LASER PATHS HAVING AN INDEPENDENTLY ADJUSTED PARAMETER

ABSTRACT

A disk texturing process uses a single pulsed laser (129) to texture disks (128, 128b) within a first group, which are carried through the texturing process on a first spindle assembly (128a), and from a second group, which are carried through the texturing process on a second spindle assembly (128c). Preferably, disks (128) from the first group are textured alternately with disks (128b) in the second group. A first level of least one texturing parameter is stored for use only as the process is applied to disks (128) from the first group, while a second level of the same texturing parameter is stored for use only as the process is applied to disks (128b) from the second group. These levels may be derived from measurements of textured spots made with interferometric devices forming portions of a texturing station.

Fig. 6